PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Isao YOKOKAWA et al.

Application No.: New US Application

Filed: February 23, 2004 Docket No.: 118749

For: METHOD FOR PRODUCING SOI WAFER AND SOI WAFER

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- 2. Relevance of the non-English language references is discussed in the present specification.
- 3. English-language Abstracts of the non-English language references Nos. 1-2 are attached hereto.
- 4. A computer-generated English translation of the following Japanese Patent Publication has been obtained from the website of the Japanese Patent Office ([http://www.jpo.go.jp]), and is attached, but has not been reviewed for accuracy. See References 1-2.

Respectfully submitted,

William P. Berridge Registration No. 30,024

Thomas J. Pardini Registration No. 30,411

WPB:TJP/tmw

Date: February 23, 2004

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INFORMATION DISCLOSURE STATEMENT												
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U.S. PATENT DOCUMENTS												
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		DOCUMENT NUMBER		DATE COUNTRY			CLASS	SUB CLASS				
	1	JP A 11-307472 (with abstract and translation))5/1999	Japan							
	2	JP A 5-211128 (with abstract and translation)		20/1993	Japan							
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	<u> </u>											
	Т.	OTHER DOCUMENTS (In										
	3	Eltran et al, "Science in Silicon", Surface Science Technology Series, Realize Inc., pp 443-496										
												
												
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Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.												

Date: February 23, 2004